

POSITIONING DEVICE

ABSTRACT

The invention relates to a positioning device (100) for positioning a substrate (101), in particular a wafer, comprising: a process chamber; a base body (105); a
5 carrier element (107) which comprises a support (109) for supporting the substrate (101), the carrier element (107) being arranged above the base body (105) and formed movable in terms of distance from the base body (105); and a holder (111) for an additional substrate (103), in particular an additional wafer or a mask, the holder (111) being arranged opposite the carrier element (107);
10 wherein there is, between the base body (105) and the carrier element (107), a sealed-off cavity (113) to which a pressure, in particular a negative pressure, can be applied so as to prevent undesired movement of the carrier element (107) as a result of the action of an external force.

(Fig. 1)